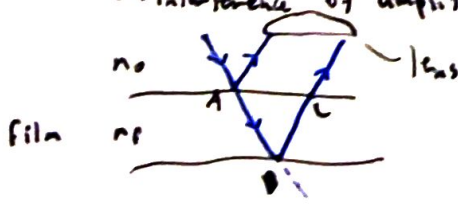


## Interference in dielectric films

↳ interference by amplitude division



substrate -  $n_s$

$$\Delta = n_f (2t)$$

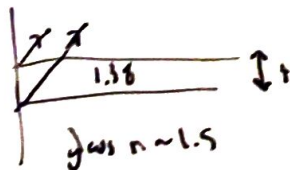
we may have phase change on reflection:  $n_s > n_0 \Rightarrow \pi$  phase shift  
 $n_s < n_0 \Rightarrow \pi$  phase shift

just like an extra half-wavelength ( $\frac{\lambda}{2}$ )

the phase shift due to the optical path difference is

$$\Delta \phi = k \Delta = k(2n_f t) = \frac{2\pi}{\lambda} 2n_f t$$

eg. if you wanted destructive interference with a film of  $MgF_2$  on glass



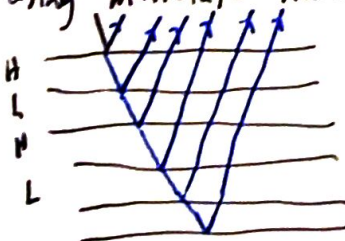
$$n_{MgF_2} = 1.38 @ 550 \text{ nm}$$

$$\text{need } 2t \left( \frac{2\pi}{\lambda} n_f \right) = \pi$$

don't need to worry about phase changes from reflection because you get  $2\pi$

$$\Rightarrow t = 99.6 \text{ nm}$$

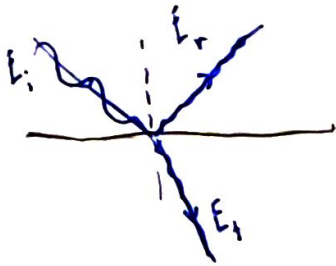
using multilayer stacks of dielectrics can get very high reflectivities  
 make these all interface constructions



Start more complex than thin interferometers

but just before that

Stokes' relations:



reflection coefficients transmission coefficients

$$r = \frac{E_r}{E_i}, \quad t = \frac{E_t}{E_i}$$